## **Directed Self-Assembly of Nanopore Arrays**

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- Motivation: Ordered Nanopore Arrays using Imprint Stamps
- Fabricate pore arrays with long-rangeorder (millimeter scale) in alumina
- Precisely control the lattice constant of the arrays as well as pore size and



Atomic force microscopy (AFM) of imprinted AI using an e-beam VNIN defined stamp.

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Upon anodization of the AI, nanopores were directed to self-assemble by the imprints to obtain long range order (up to 1mm x 1mm). SEM photos shown.

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 Results: Nanoimprinting method was successful

